

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-15317 US		10-1754 365	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					Yin S. Tang			
					Filing Date		Group	
					1/08/2004		2873	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DNS	AA	4,541,727	09/17/1985	Rosenthal	368	232		
DNS	AB	6,129,866	10/10/2000	Hamanaka et al.	264	1.7		
DNS	AC	6,335,828	01/01/2002	Hashimoto et al.	359	443		
DNS	AD	6,582,988	06/24/2003	Hsiao et al.	438	70		
DNS	AE	6,654,174	11/25/2003	Huang	359	619		
	AF							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AG							
	AH							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
DNS	AI	B. Volckaerts et al., <u>The Fabrication of Cylindrical Micro-Lens Arrays with Deep Lithography with Protons</u> , Cyclotron Department VUB, Laarbeeklaan 103, 1090 Brussels, Belgium, 2002.						
	AJ	DAVID SPECTOR PRIMARY EXAMINER						
Examiner	[Signature]		Date Considered 2/10/2005					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								